

10080848
02/22/02
10080848
02/22/02

PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10080848	FILING DATE 02/22/2002	CLASS 257.138	SUBCLASS 706	GAU 1765	EXAMINER Deo
----------------------	---------------------------	------------------	-----------------	-------------	-----------------

**APPLICANT'S: Otake Hiroto; Saitoh Shinobu; Tada Munehiro; Hayashi Yoshihiro;

**CONTINUING DATA VERIFIED:
Jd

** FOREIGN APPLICATIONS VERIFIED:

JAPAN 047358/2001 02/22/2001
2002/01/15-5639

PG-PUB	DO NOT PUBLISH <input type="checkbox"/>	RESCIND <input type="checkbox"/>	
Foreign priority claimed 35 USC 119 conditions met Verified and Acknowledged Examiners's initials		<input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> yes <input type="checkbox"/> no	ATTORNEY DOCKET NO KRM-00101
TITLE : Method of manufacturing a semiconductor device capable of etching a multi-layer of organic films at a high selectivity			
U.S.DEP.T. OF COMM./PAT & TM-PTO 4500, P. 12-34 94			

NOTICE OF ALLOWANCE MAILED		Assistant Examiner	CLAIMS ALLOWED	
			Total Claims	Print Claim for O.G.
ISSUE FEE		DRAWING		
Amount Due	Date Paid	Sheets Drwg.	Figs. Drwg.	Print Fig.
TERMINAL DISCLAIMER		Primary Examiner		
		PREPARED FOR ISSUE		
		Application Examiner		
WARNING: The information disclosed herein may be restricted. Unauthorized disclosure may be prohibited by the United States Code Title 35, Sections 122, 181 and 368. Possession outside the U.S. Patent & Trademark Office is restricted to authorized employees and contractors only.				

FILED WITH: DISK (CRF) CD-ROM
(Attached in pocket on right inside flap)

BEST AVAILABLE COPY